

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims**

1. (Original) A large profile, high speed laser micrometer, comprising:
  - (a) a light source unit comprised of an emitter module that emits a laser sheet;
  - (b) a detector array comprised of a detector module, wherein said emitter module and said detector module are aligned; and
  - (c) a data processing unit;

such that an object passing between said light source unit and said detector array can be measured to a n accuracy of at least 4/100ths of an inch.

2. (Original) The laser micrometer according to claim 1, wherein said emitter module is comprised of one or more laser line generators, said laser line generators arranged in an overlapping fashion to prevent gaps in the laser sheet emitted by said emitter module when the number of said laser line generators is two or more.

3. (Original) The laser micrometer according to claim 2, wherein said laser line generators are arrange in an overlapping stair-step fashion.

4. (Original) The laser micrometer according to claim 2, wherein said detector module is comprised of one or more linear CIS detectors, the number of said linear CIS detectors equal to the number of laser line generators, said linear CIS detectors arranged in an overlapping fashion corresponding to said laser line generators.

5. (Original) A large profile, high speed laser micrometer, comprising:
- (a) a light source unit comprised of a plurality of emitter modules that combine to emit a laser sheet;
  - (b) a detector array comprised of a plurality of detector modules wherein each of said plurality of emitter modules and each of said plurality of detector modules are aligned; and
  - (c) one or more data processing units;

such that an object passing between said light source unit and said detector array can be measured to an accuracy of at least 4/100ths of an inch.

6. (Original) The laser micrometer according to claim 5, wherein each of said emitter modules is comprised of two or more laser line generators, said laser line generators arranged in an overlapping fashion to prevent gaps in the laser sheet emitted by said emitter module.

7. (Original) The laser micrometer according to claim 6, wherein said laser line generators are arranged in an overlapping stair-step fashion.

8. (Original) The laser micrometer according to claim 6, wherein each of said detector modules is comprised of two or more linear CIS detectors, the number of said linear CIS detectors equal to the number of laser line generators, said linear CIS detectors arranged in an overlapping stair-step fashion corresponding to said laser line generators.

9. (Original) The laser micrometer according to claim 5, wherein the number of data processing units is equal to a fraction of the number of said detector modules such that each data processing unit provides data processing for a number of detector modules located adjacent to one another.

10. (Original) The laser micrometer according to claim 9, where said fraction is one-third.

Claims 11-12 (Withdrawn)